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Remote-controlled fabrication of 2D heterostructure

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Foreword

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Abstract

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Used abbreviations

- LION : Leiden Institute Of Physics
- VDWSF: Van Der Waals Stacking Facility
- FMD : Fine Mechanical Department
- ELD : Electronics Department
- TUI : Terminal User Interface (differend from CLI in the sense that the user doesn't directly interact with the command line)
- GUI : Graphical User Interface
- SDK : Software Development Kit
- DAS : Domain Applied Science

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1 Introduction

The discovery of graphene in 2004, awarded the Nobel Prize in Physics in 2010, has led to a completely new field of research based on 'atomically thin materials', materials of a few atomic layers thick (2D materials). Recently, the focus of the research area has shifted to fabricating completely new structures by stacking different atomically thin materials 'Van Der Waals Heterostructures'. Atomic thin materials can consist of metals, semiconductors, insulators, ferromagnets, superconductors, etc., combining these materials is a route to developing useful devices [Geim and Grigorieva].

Recently, a new research group was started under Principle Investigator Dr. Semonti Bhattacharyya who is an expert in fabricating and characterizing Van Der Waals Heterostructures and 2D materials and who recently started her new laboratory at LION, the Van Der Waals Stacking Facility (VDWSF). This project will focus on the efficient and accurate fabrication and imaging of the Van Der Waals Heterostructures and will be carried out by the Van Der Waals stacking lab at the Leiden Institute of Physics (LION). LION is one of the oldest physics research institutes in the Netherlands. The research performed at Leiden Institute of Physics covers a broad spectrum of topics, from cosmology to condensed matter physics, from quantum computers to new systems such as Van Der Waals Heterostacks. Research at LION is largely fundamental and curiosity-driven but also with an eye toward societal value.

This project will take place at the Leiden Institute of Physics (LION), which is one of the oldest physics institutes in the Netherlands. Research at the Leiden Institute of Physics covers a broad spectrum of subjects, ranging from cosmology to condensed matter physics, from the physics of jamming in granular materials to quantum computation, from protein folding to superconductivity and novel systems like van der Waals materials. Recently a new research group has been appointed to Semonti Bhattacharyya who is an expert in fabrication and characterisation of van der Waals and 2D materials and who has recently started to setup her new laboratory at LION, the Van Der Waals Stacking Facility (VDWSF). This project will focus on the efficient and accurate fabrication and imaging of the Van Der Waals Heterostructures with adaptability in mind to make the instrument more flexible and fit future research projects.

2 Project definition

Presently a commercial setup for fabricating 2D Hetero-stacks is used in the Van Der Waals Stacking Facility (VDWS) at lion. This commercial setup is prone to vibrations and has an inferior-quality microscope, which makes it difficult to clearly identify small 2D material. Furthermore, the laboratory has a vibration level slightly above VC-C [\[Isolation\]](#). For these reasons a new setup will be developed that should be less sensitive to mechanical vibrations. This setup is focused on improved rigidity, accuracy and flexibility compared to the commercially available and previous versions. The setup will be based on a commercial (Olympus BXFM) optical microscope, but to reach this goal a custom microscope stand, sample holder, mask holder and software have to be developed.

2.1 Research question

What components and control techniques should be used to make the stacking setup as least susceptible to vibration as possible and controllable at the sub-micrometer scale while producing clear images with an optical microscope?

2.2 Research goal

Building a stacking setup that is as least susceptible to vibration as possible where the base x-y-z stages move with resolution on the micrometer scale and the mask x-y-z stages on the nanometer scale, which can be remotely controlled, while being able to capture clear images with an optical microscope.

3 Background

Over the past decade, research into two-dimensional (2D) materials and van der Waals heterostructures has opened up a world of possibilities for the development of new technologies. 2D materials, such as graphene and hexagonal boron nitride, are atomically thin and have unique electrical, optical, and mechanical properties that make them interesting for a variety of applications.

3.1 van der Waals Heterostructures

Van der Waals heterostructures are composed of two or more 2D materials that are stacked together and can be used to create electronic and optoelectronic nano devices. This research has enabled the development of a wide range of technologies, including flexible electronics, high-speed transistors, and ultra-sensitive sensors. The promise of 2D materials and van der Waals heterostructures is that they can be used to create devices that are faster, more efficient, and more reliable than existing technologies [Geim and Grigorieva].

3.2 Fabrication of van der Waals Heterostructures: Stamping

The stamping process is a method used to fabricate van der Waals heterostructures. This process involves the transfer of 2D crystals onto a substrate by pressing them together with a stamp so the van der Waals forces between the layers become strong enough to hold the layers together.

The general stamping procedure is as follows:

1. The 2D material flakes are placed on top of the substrate
2. The operator looks for suitable flakes to use for the stamping
3. The operator places the stamp on top of the 2D material flake and changes the sample temperature to stick the flake to the stamp
4. The stamp with the flake is positioned above the second 2D material flake on the substrate
5. The operator places the stamp on top of the second 2D material flake and changes the sample temperature to release the flake from the stamp
6. The operator finds a new suitable flake to place on top of the created stack and repeats the process

This process consists of several time consuming steps, such as finding suitable flakes, placing the flakes on the stamp and substrate, and changing the sample temperature. The aim of this project is to automate the process of stamping to reduce the time needed to fabricate a stack and to increase the accuracy of the process.

3.3 Vibration isolation

Bij het ontwerpen van de stand van de microscoop moet sterk rekening gehouden worden met de rigiditeit en eigenfrequentie van de opstelling. Bij commercieel verkrijgbare stacking opstellingen is een faseverschil tussen trilling door het monster, masker en camera een bekend en veel voorkomend probleem, dit heeft als effect dat de uitlijning van flakes en het stapelen bemoeilijkt worden en de kans op beschadigen van de flake aanzienlijk groter is.

Het doel van het in house fabriceren van de microscoop stand is dan ook het behalen van een betere performance op het gebied van trillingsisolatie en rigiditeit tegenover commercieel verkrijgbare standaarden.

Bij het bestuderen van trillingsrespons van een opstelling kan er gekeken worden naar kracht gedreven trilling (er wordt een periodieke kracht uitgeoefend op een vast punt op het instrument) of er kan gekeken worden naar amplitude gedreven trilling (trillen van het oppervlak onder het instrument). Het is belangrijk

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om het onderscheid tussen beide methodes te maken omdat deze wiskundig verschillend worden beschreven en ook anders dynamisch gedrag vertonen [Hesselberth, a], in het geval van dit project zal er gekeken worden naar een sterk gesimplificeerd model voor een amplitude gedreven trilling (zie figuur 1).

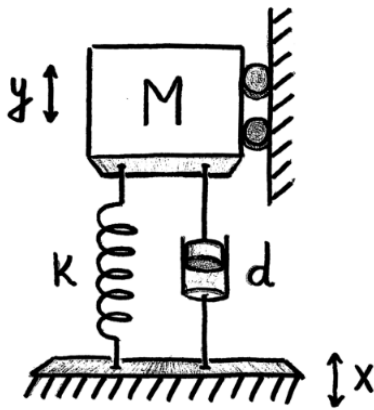


Figure 1: Schematic of a simplified microscope as a mass spring damper system on a vibrating base. [Hesselberth, b]

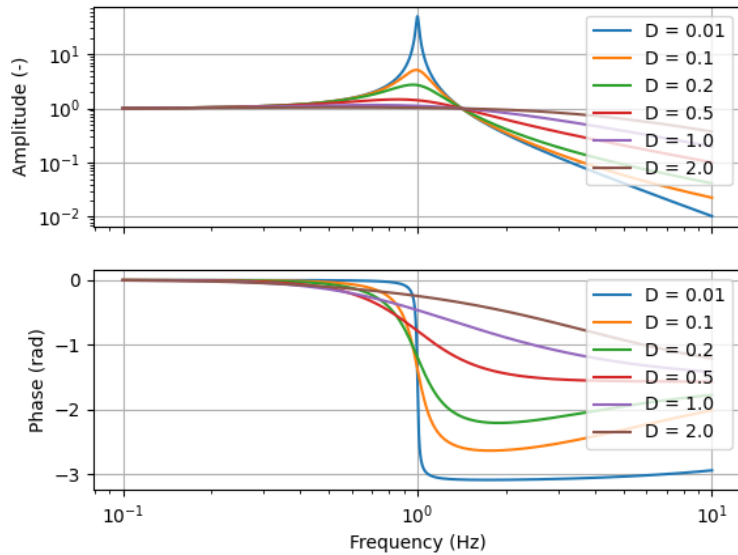


Figure 2

Door de opstelling te zien als een gedempt massa veer system (zie figuur 1) kan met regeltechniek theorie het verwachte dynamische gedrag benadert worden. Om de berekeningen te versimpelen word de opstelling verdeelt in 2 inertiaalsetelsels, stelsel Y met coördinaat y voor de uitwijking van de massa m met respect tot de evenwichtspositie van de massa en X met coördinaat x voor de uitwijking van de basis met respect tot de evenwichtspositie. Omdat het gedrag als functie van tijd voor dit systeem niet van belang alleen de overdracht als functie van frequentie kan er gekeken worden naar de overdracht van het systeem in het Laplace domein. Het model bestaat uit de gecombineerde krachten balans in de Z richting zoals beschreven in formule 1. Door de balans vervolgens te transformeren naar het Laplace domein en te herordenen kan de overdrachtsfunctie zoals beschreven in formule 3 verkregen worden.

$$m \frac{d^2 y}{dt^2} + d \frac{dy}{dt} + ky = d \frac{dx}{dt} + kx \quad (1)$$

$$\omega_0 = \sqrt{\frac{k}{m}}; \quad D = \frac{d}{\sqrt{2mk}}; \quad f = \frac{\omega}{\omega_0} \quad (2)$$

$$H = \frac{Y}{X} = \frac{dj\omega + k}{-m\omega^2 + dj\omega + k} = \frac{\omega_0^2 + 2jD\omega_0^2 f}{\omega_0^2 + 2jD\omega_0^2 f - \omega^2 f^2} \quad (3)$$

$$A = \frac{\sqrt{1 + (2Df)^2}}{(1 - f^2)^2 + (2Df)^2}; \quad \phi = \arctan\left(\frac{-2Df^3}{1 - f^2 + (2Df)^3}\right) \quad (4)$$

Zoals te zien in formule 3 te zien is zal de amplitude oneindig naderen wanneer het systeem geen dempingsfactor heeft. Het instrument zelf zal geen damping hebben maar geplaatst worden op een actieve vibratie isolatie tafel, voor correcte werking is het van belang dat de resonantiefrequentie van het instrument buiten de doorgelaten band van de actieve tafel valt. Voor de gebruikte actieve demper is dit 90% vanaf 2 Hz en 99% vanaf 10 Hz [DVI]

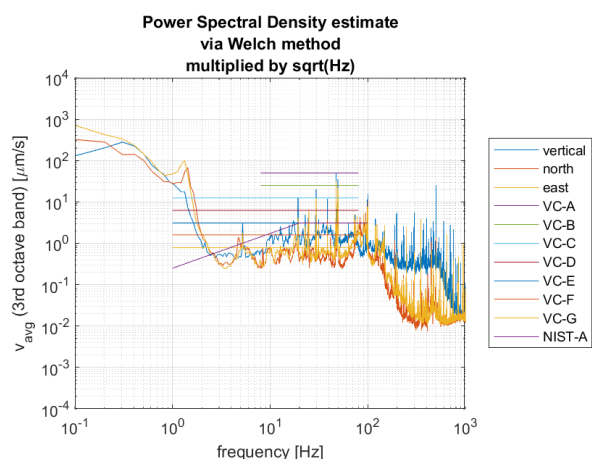


Figure 3: Measured vibration data in the Van der Waals Stacking Facility laboratory on the position of the stacking instrumentation. By J. Scheffer

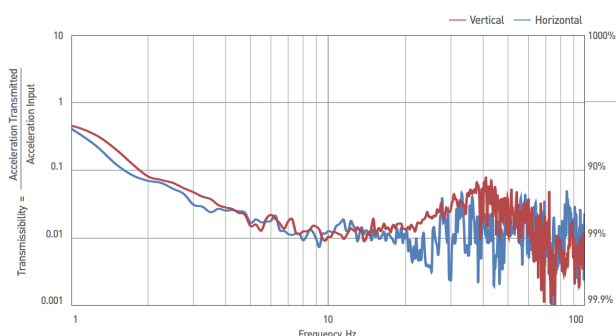


Figure 4

3.4 Criteria

Door het analyseren van de workflow van handmatige en gemotoriseerde commerciële stamping opstellingen in combinatie met literatuurstudie is een lijst aan minimale eisen opgesteld waar het te ontwikkelen instrument aan moet voldoen.

1. Mask holder

- The mask should be motorized and able to move in the x, y and z direction with a resolution of > 30 nm.
- The pitch of the mask should be able to be adjusted with a resolution of $> 0.05^\circ$.
- The yaw of the mask should be able to be adjusted with a resolution of $> 0.05^\circ$, with a minimum range of 180° .

2. Sample holder

- The sample holder should be able to hold a minimum of 2 samples.
- The sample should be able to heat with a ramp speed of $2.0 - 50.0^\circ\text{C/s}$
- The sample should be able to cool with a ramp speed of $-0.1 - 30.0^\circ\text{C/s}$

3. Microscope & stand

- Due to the fact that the VDWSF laboratory has problems with external vibrations (see 3 the microscope stand should be as rigid as possible to make the instrument behave like one rigid body instead of a system of multiple bodies.
- The microscope should have a 20x objective with correction collar to be able to focus on the sample through the mask holder glass slide.

4 Methods & Results

4.1 Stand design

Voor het fabriceren van stacks is het belangrijk dat de opstelling zo min mogelijk beïnvloed wordt door trillingen uit de omgeving. Om deze reden is er voor gekozen om in samenwerking met LION FMD een aantal uitwijkingssimulaties uit te voeren om een inschatting te kunnen maken over de maximale uitwijking onder een statische kracht van de microscoopstand.

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Het complete instrument bestaat uit verschillende aspecten die in de volgende hoofdstukken behandeld zullen worden. Voor een overzicht van de gebruikte hard- en software componenten zie [13](#).

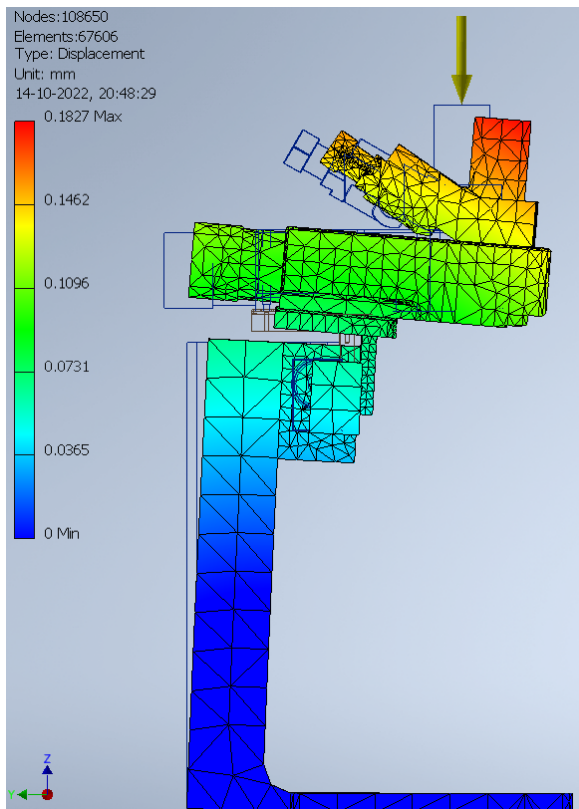


Figure 5: 100 N pressing force on a static point on the microscope. To reduce displacement a 30mm fillet was added between the base-plate and stand, reducing the maximum displacement to 183 μm . By R. Stoelwinder

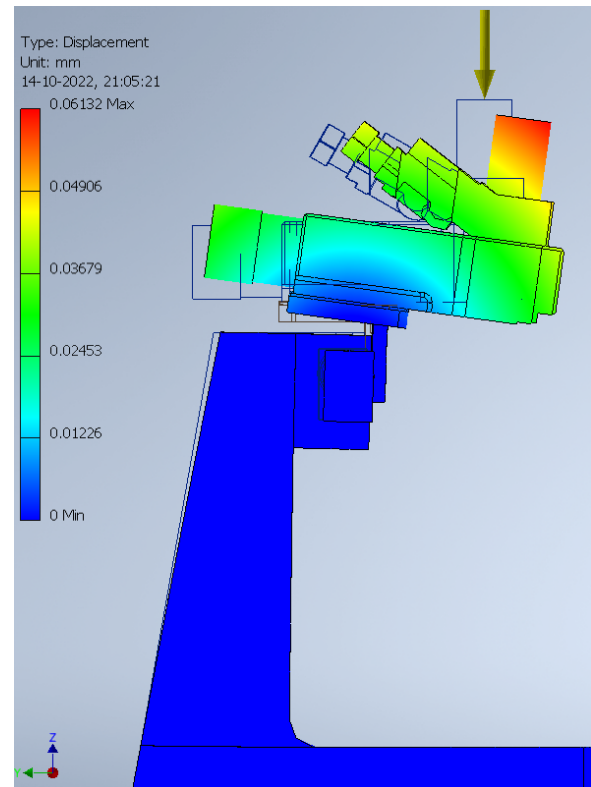


Figure 6: 100N pressing force on a static point on the microscope head. To reduce the the maximum displacement the thickness of the base-plate is increased from 20mm to 50mm, reducing the maximum displacement to 50 μm . By R. Stoelwinder

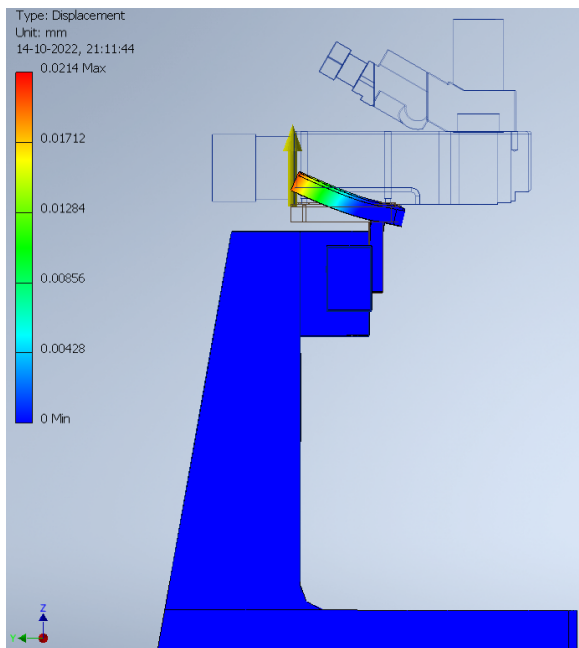


Figure 7: 100N pulling force on a static point on the corner plate causing a $21\mu\text{m}$ displacement. By R. Stoelwinder

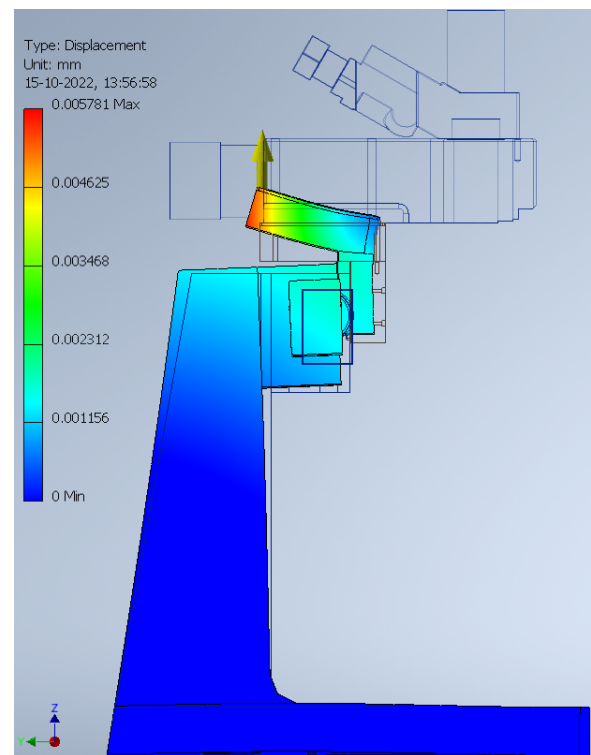


Figure 8: 100 N pulling force on a static point on the corner-plate. To reduce the maximum displacement the thickness of the corner plate is increased from 20mm to 40mm, reducing the maximum displacement to $5\mu\text{m}$. By R. Stoelwinder

4.2 Mask design

the mask consists of two major parts: the mask holder which holds the stamping polymer and the stages which are used to position the mask above the sample

For the mask holder

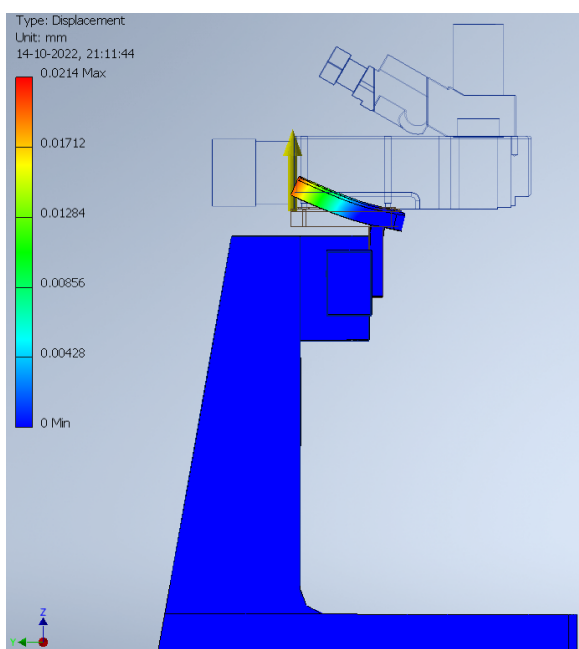


Figure 9: The mask holder schematic. By R. Stoelwinder

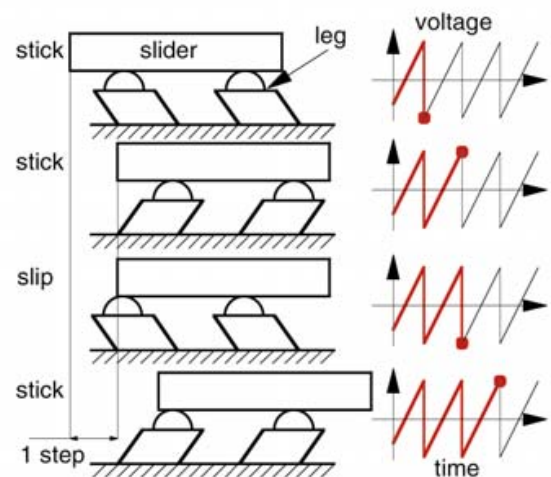


Figure 10: Operating principle of a slip-stick actuator mechanism [Mazerolle et al.]

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4.3 Sample holder design

de hoofdtak van de samplehouder is zoals de naam zegt het in positie houden van het monster waarmee gewerkt wordt (in dit geval een waver). Net zoals de rest van het instrument is het van belang om de sample houder zo rigide mogelijk te maken om ervoor te zorgen dat de trillingen van de masker en de camera in fase blijven.

Tijdens de duur van dit project is het eerste prototype van de samplehouder gefabriceerd en zijn de plannen voor het vervolg ontwerp gemaakt. Het prototype (zie figuur 9) bestaat uit 3 onderdelen: Het sample bed, isolatielaag en de dump cilinder. Het sample bed bevat de benodigde componenten om de het sample naar op gewilde temperatuur tussen 0 en 200 graden C krijgen, hiervoor worden een heating coil (verwarmen) en peltier element (koelen) gebruikt. Het samplebed bevat ook een vacuum aansluiting die gebruikt kan worden om het sample stugger te bevestigen wanneer de gebruiker trillingsproblemen ondervindt.

De functie van de isolatielaag is het isoleren van het samplebed en de dump cilinder om te voorkomen dat warmte vanuit de dumpcilinder teruglekt in het sampleblok (van belang tijdens koelen van het monster)

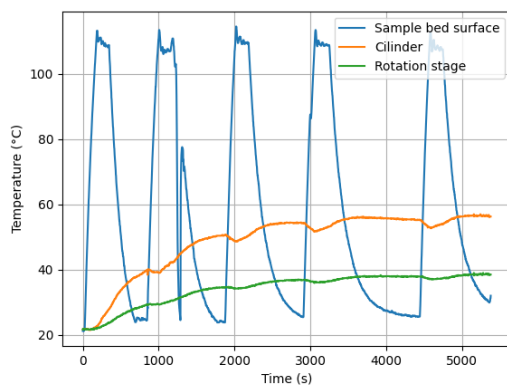


Figure 11: Temperature graph of the sample holder when simulating workload by heating to 110 degrees and cooling down to ambient temperature (25 degrees) while waiting for 120 seconds when the level is reached

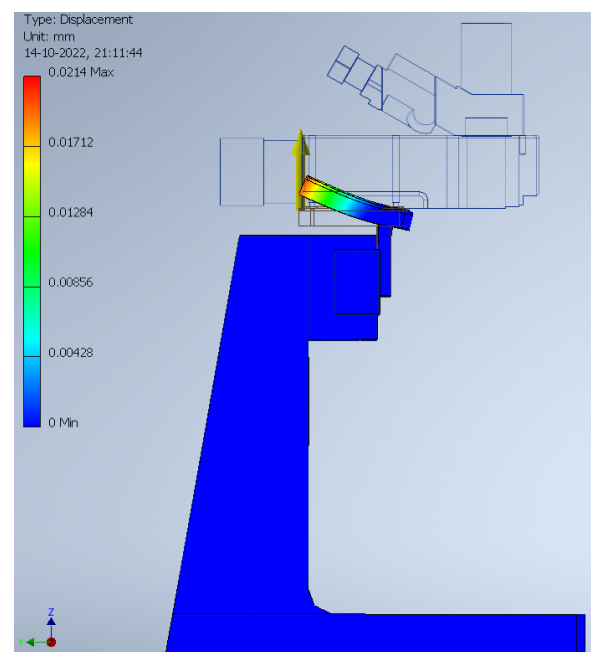


Figure 12: CAD schematic of the sample holder. By R. Stoelwinder. The sample holder prototype consists of 4 major parts. 1. The sample bed, which contains a heating coil, peltier element, thermocouple and PT100 sensor. 2. The sample isolation layer. This is a shroud fabricated out of PEEK

4.4 Base stage automisation

for this project the base xy stage () has to be automated, this will be developed in house in collaboration with LION FMD and ELD.

The stages were automated using NEMA17 stepper motors, and optical endstops. The stepper motors and endstops are controlled by the controller developed by ELD. The contents and used techniques in the control box are out of the scope for this report.

The first prototype bracket makes it possible to test the complete system and work out implementation bugs. It is recommended to create further iterations of the brackets as the current version can flex $\pm 3\text{mm}$ and this has a detrimental effect on the rigidity of the base xy stage, this because the stages are held in place by the stepper motor. Furthermore it is also recommended to replace the ball bearings in the spindles as these

keuze voor peels en mica onderbouwen

CAD schema van de sample holder invoegen

CAD van bracket invoegen

ref naar op-tosigma stage invoegen

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were damaged during fabrication and the spindle is now only held in place by the stepper motor

4.5 Stage calibration

Due to the mechanisms used in some of the actuators it is not possible to calibrate all the staged, nor is this needed for the application. The stages that cannot be calibrated are the x, y, and z axis of the mask due to the used slip-stick mechanism (see figure 10).

The slip stick mechanism makes it possible to use piezo actuators with high resolution for an unbound range. The drawback is that due to the slip stick mechanism (friction based) the actuator has a position uncertainty of and a sstep uncertainty of.

4.6 Software

Because one of the main criteria of the project is flexibility and modularity this has to be taken in consideration from the beginning. This means the project needs to be created in a structured and standardised way using design patterns and a modular architecture (see appendix A for the definition of these terms).

4.6.1 Architecture

As a main architecture a web application inspired framework is used. This means that the system consist of three major components: Frontend, Middleware and backend (for more information about these definitions see appendix A). Using standard design patterns makes getting to know the code and editing it less cumbersome and error prone for future developers. An overview of the system flow can be seen in figure 13

4.6.2 Frontend

The frontend is the part of the system that is visible to the user. This part of the system is responsible for the user interface and the communication with the middleware. The system has two pre made interface options: GUI and TUI. For operators of the system it is recommended to use the GUI as no knowledge of the command set is needed and safety features like thermal-runaway and forbidden areas are enabled. For developers it is recommended to use the TUI as it is more flexible and allows for more control over the system.

The GUI is created using QT6 with Pyside6 bindings to ensure interoperability between different operating systems and detailed documentation for future developers.

The TUI consists of a simple loop that pushes the gcode commands to the backend and uses a thread to monitor the backend response.

4.6.3 Middleware

The middleware is a method that can be used to communicate between the frond and backend. The middleware base class (see B) contains all the base methods needed for the system to work with a middleware method. The system contains two default middleware methods: The processing pipe, wich is used for when the backend runs on the same computer as the frondend but on a seperate core (it is strongly discouraged to run the backend on the same core as the frondend as this makes the backend behavoir depend on core workload.) The second method is the serial method and is based on the PySerial library and is used when the backend runs a differend computer than the frondend. The serial middleware method can be easily adapted to work with wireless serial communication but this is dicuraged as this method is more prone to errors.

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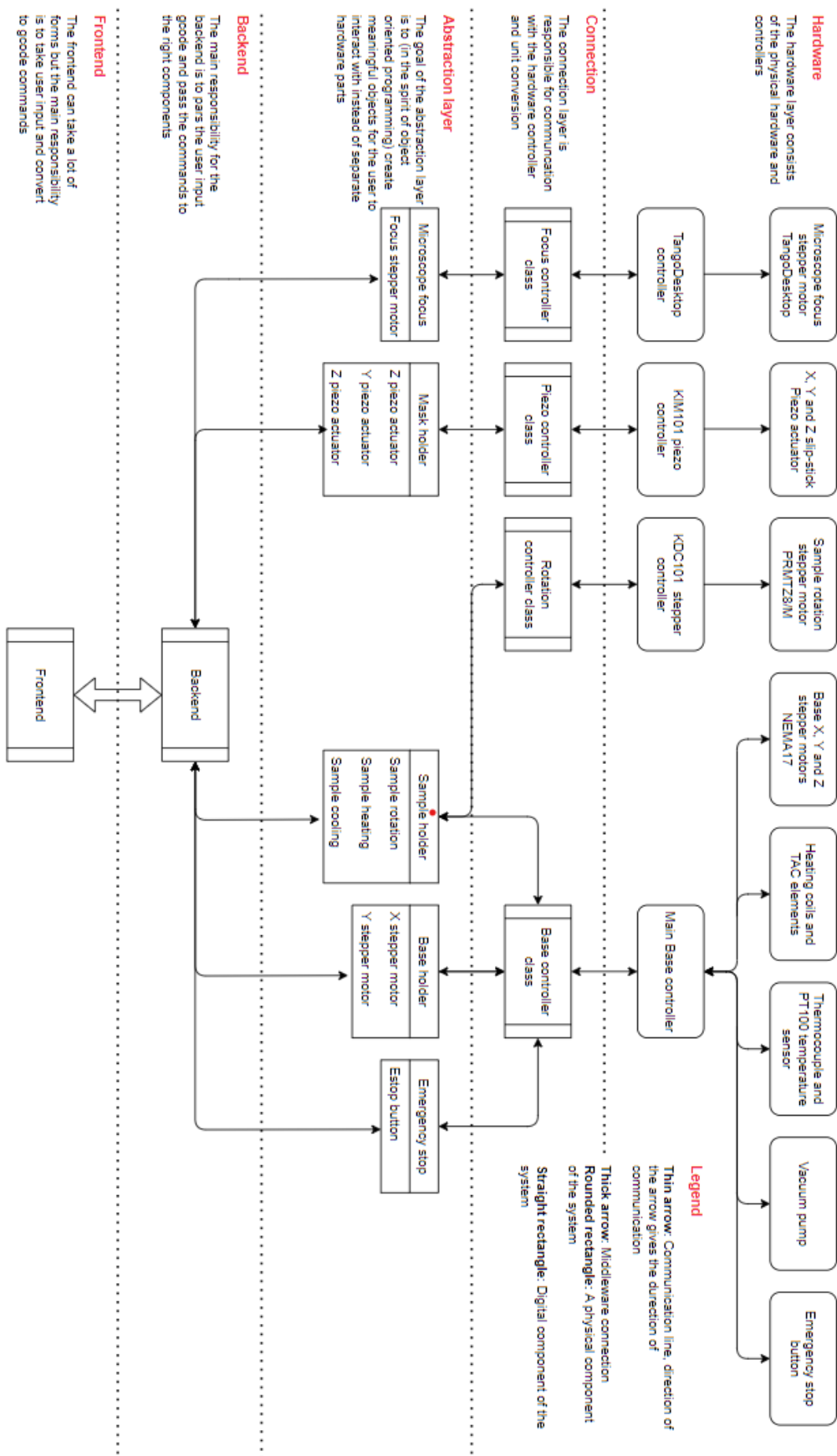


Figure 13: Software flow of the project.

4.6.4 Backend

The backend is the part of the system that is responsible for the communication with the hardware and the middleware and managed the object the user can interact with (sample holder, mask holder, etc.) The backend accepts all classes that inherit from their respective base class and abide the programming guidelines

Due to time constraints it was not possible to develop the backend to run on unix based systems

4.6.5 Forbidden areas

To prevent the system from damaging itself or the sample it is important to prevent the system from moving to certain areas in certain states.

Phase space variables (system attributes):

- Position of all the axis*
- Velocity of all the axis
- Acceleration of all the axis
- Sample temperature
- Sample heating and cooling ramp

This means the phase space will consist of 21 dimensions, where each dimension represents the current value of a system attribute.

First the phase space is bordered off by the hardware limitations like maximum velocity, minimal reproducible step size, range, etc. Further forbidden areas are studied using a fractional factorial design to determine the most important variables that influence the system.

The forbidden areas will be determined using a fractional factorial design with the following parameters (see excel file)

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5 Conclusion

6 Discussion

References

- DVIA-T Tabletop Active Vibration Isolation Platform | Products. URL <https://www.daeilsys.com/products/active-vibration-isolation-systems/tabletop-active-vibration-isolation-platform/>.
- A. K. Geim and I. V. Grigorieva. Van der Waals heterostructures. 499(7459):419–425. ISSN 1476-4687. doi: 10.1038/nature12385. URL <https://www.nature.com/articles/nature12385>.
- M. Hesselberth. Basic calculations for vibration isolators. a.
- M. Hesselberth. Microscopie in beweging. b.
- M. K. V. Isolation. Vibration Criterion (VC) curves | Minus K. URL https://www.minusk.com/content/technology/vc_curves_minus_k_vibration_isolation.html.
- S. Mazerolle, R. Rabe, T. Varidel, and J.-M. Breguet. Positioning, Handling and Measuring inside a Scanning Electron Microscope.

A Programming terms

Design patterns

In programming, a design pattern is a general repeatable solution to a commonly occurring problem in software design. A design pattern is not a finished design that can be transformed directly into code. It is a description or template for how to solve a problem that can be used in many different situations.

Design patterns are used to describe solutions to specific design problems in object-oriented programming. They provide a way to reuse successful designs and design solutions that have been proven to work well in the past.

There are many different types of design patterns, including creational patterns, structural patterns, and behavioral patterns. Creational patterns deal with object creation mechanisms, trying to create objects in a manner suitable to the situation. Structural patterns deal with object composition, creating relationships between objects to form larger structures. Behavioral patterns focus on communication between objects, what goes on between objects and how they operate together.

Using design patterns can make it easier to design and develop software, because they provide a common vocabulary and framework for thinking about and solving design problems. They also help to make code more maintainable and scalable by providing a clear, consistent way to structure and organize it.

Modular architecture

In a web application or system, the frontend refers to the part of the application that the user interacts with, typically through a web browser. It includes all the elements that the user can see and interact with, such as the layout, user interface, and visual design of the application.

The backend, on the other hand, refers to the part of the application that handles the logic and processing behind the scenes. It is responsible for tasks such as storing and retrieving data from a database, performing calculations and processing, and interacting with other systems or APIs.

Middleware is software that sits between the frontend and the backend and helps to facilitate communication and data exchange between them. It can provide functions such as authentication, routing, and data transformation, and can help to abstract away some of the complexity of the backend from the frontend.

In a web application, the frontend and backend are typically implemented using different technologies and run on different servers or infrastructure. Middleware can be implemented using a variety of technologies, depending on the specific requirements of the application.

Multi-threading and processing

In computer science, multi-threading is a technique that allows a single process or program to have multiple threads of execution. A thread is a separate flow of execution within a process, and each thread can run

concurrently or in parallel with the other threads within the same process.

Multi-threading can be used to improve the performance of a program by allowing it to perform multiple tasks concurrently. For example, a program that has a user interface and needs to perform some time-consuming calculations in the background could use multi-threading to allow the user to continue interacting with the interface while the calculations are being performed.

Multi-processing is a technique that allows a computer to run multiple processes simultaneously. A process is an instance of a program that is being executed by the operating system. Each process has its own memory space and runs in a separate environment, and multiple processes can be run concurrently on different cores or processors within a computer.

Multi-processing can be used to improve the performance of a program by allowing it to take advantage of multiple processors or cores within a computer. This can be particularly useful for programs that need to perform a lot of calculations or that are designed to run on a distributed system with multiple machines.

B Backend base classes

The base classes are used as a template for new components. The base classes contain all the functions that are required for the component to work with the rest of the system. Notice that two different errors can be raised: `NotImplementedError` and `NotSupportedError`. The functions that raise a `NotImplementedError` should always be implemented for the component to work correctly with the rest of the system. It is safe to raise `NotSupportedError` as these are caught and handled by the system.

Hardware base class

```

1 class NotSupportedError(Exception):
2     """Exception raised when a method is not supported."""
3
4     def __init__(self, msg=None):
5         """Initialize the exception."""
6         self._msg = msg
7
8     def __str__(self):
9         return self._msg
10
11
12 class HardwareNotConnectedError(Exception):
13     """Exception raised when a hardware is not connected."""
14
15     def __init__(self, msg=None):
16         """Initialize the exception."""
17         self._msg = msg
18
19     def __str__(self):
20         return self._msg
21
22
23 class NotCalibratedError(Exception):
24     """
25     Exception raised when the hardware is not calibrated for the asked function.
26
27     F.e. trying to do an absolute move when the home point is unknown.
28     """
29
30     def __init__(self, msg=None):
31         """Initialize the exception."""
32         self._msg = msg
33
34     def __str__(self):
35         return self._msg
36
37
38 class HardwareError(Exception):
39     """General exception raised when the hardware is not working properly."""
40
41     def __init__(self, msg=None):
42         """Initialize the exception."""
43         self._msg = msg
44
45     def __str__(self):
46         return self._msg
47
48
49 class Base:

```

```

50 """
51 Base class for hardware.
52
53 This class contains all the functions the StackingSetupBackend class expects
54 connected hardware to have. Functions that are supported should be overridden
55 in the derived class.
56
57 .. important::
58     Functions that should be supported by all hardware raise a ‘‘NotImplementedError’’
59     optional functions raise ‘‘NotSupportedError’’. The ‘‘NotSupportedError’’ is
60     by the ‘‘StackingSetupBackend()’’ class, so it is safe to raise it in functions
61     not supported by all hardware.
62
63 .. note:: Each function should return an exit code (0 for success, 1 for failure)
64     and an error message, str, or None.
65
66 """
67
68 _id = None
69 _type = "HARDWARE BASE CLASS"
70
71 # COMPONENT LIMITS
72 _max_speed = None
73 _max_acceleration = None
74 _max_temperature = None
75
76 # ATTRIBUTES
77 @property
78 def id(self):
79     """Get the class identifier."""
80     return self._id
81
82 @property
83 def type(self):
84     """Get the type of the hardware."""
85     return self._type
86
87 @property
88 def device_info(self):
89     """Get the device info of the hardware."""
90     raise NotImplementedError()
91
92 # STEP CALIBRATION ATTRIBUTES
93 """
94 If the connected component can move only one of the steps per ... should be supported.
95 If the component cannot move none have to be supported.
96 """
97
98 @property
99 def steps_per_um(self):
100     """Get the steps per um of the hardware."""
101     raise NotSupportedError()
102
103 @property
104 def steps_per_deg(self):
105     """Get the steps per degree of the hardware."""
106     raise NotSupportedError()
107
108 # MOVEMENT PROFILE ATTRIBUTES
109 @property
110 def position(self):
111     """Get the position of the hardware."""

```

```

112         raise NotImplementedError()
113
114     @property
115     def speed(self):
116         """Get the set speed of the hardware in um/s or deg/s."""
117         raise NotImplementedError()
118
119     @speed.setter
120     def speed(self, speed):
121         """Set the speed of the hardware in um/s or deg/s."""
122         raise NotImplementedError()
123
124     @property
125     def acceleration(self):
126         """Get the acceleration of the hardware."""
127         raise NotImplementedError()
128
129     @acceleration.setter
130     def acceleration(self, acceleration):
131         """Set the acceleration of the hardware."""
132         raise NotImplementedError()
133
134     # TEMPERATURE ATTRIBUTES
135     @property
136     def temperature(self):
137         """Get the temperature of the hardware."""
138         raise NotImplementedError()
139
140     @property
141     def target_temperature(self):
142         """Get the target temperature of the hardware."""
143         raise NotImplementedError()
144
145     @target_temperature.setter
146     def target_temperature(self, temperature):
147         """Set the target temperature of the hardware."""
148         raise NotImplementedError()
149
150     # CONNECTION FUNCTIONS
151     def connect(self):
152         """Connect the hardware."""
153         raise NotImplementedError()
154
155     def disconnect(self):
156         """Disconnect the hardware."""
157         raise NotImplementedError()
158
159     # STATUS FUNCTIONS
160     def is_connected(self):
161         """Check if the hardware is connected."""
162         raise NotImplementedError()
163
164     def is_moving(self):
165         """Check if the hardware is moving."""
166         raise NotImplementedError()
167
168     def is_homed(self):
169         """Check if the hardware is homed."""
170         raise NotImplementedError()
171
172     def get_status(self):
173         """Give a status report."""

```

```
174         raise NotImplementedError()
175
176     # HOMING FUNCTIONS
177     def home(self):
178         """Home the hardware."""
179         raise NotImplementedError()
180
181     # MOVING FUNCTIONS
182     def start_jog(self, direction):
183         """Start a jog in a direction."""
184         raise NotImplementedError()
185
186     def stop_jog(self):
187         """Stop a jog."""
188         raise NotImplementedError()
189
190     def move_to(self, position):
191         """Move the hardware to a position."""
192         raise NotImplementedError()
193
194     def move_by(self, position):
195         """Move the hardware by a position."""
196         raise NotImplementedError()
197
198     def rotate_to(self, rotation):
199         """Rotate the hardware to a position."""
200         raise NotImplementedError()
201
202     def rotate_by(self, rotation):
203         """Rotate the hardware by a position."""
204         raise NotImplementedError()
205
206     def stop(self):
207         """Unconditionally stop the hardware."""
208         raise NotImplementedError()
209
210     def emergency_stop(self):
211         """Unconditionally stop the hardware."""
212         raise NotImplementedError()
```


Middleware base class

```

1 import configparser
2 import time
3
4 SENTINEL = "SENTINEL" # Sentinel command to close the pipe
5 EOM_CHAR = "EOM" # String indicating the end of a message over a pipe
6
7
8 class HandshakeError(Exception):
9     def __init__(self, message=None):
10         self._message = message
11
12     def __str__(self):
13         return self._message
14
15
16 class BaseConnector:
17     """
18     Class to hold all the expected connection functions.
19
20     This class does not manage the connection it is a base class that should
21     be inherited.
22     """
23
24     _connection_method = None
25     _role = None
26     _handshake_complete = False
27     _SENTINEL = SENTINEL
28
29     # ATTRIBUTES
30     @property
31     def connection_method(self):
32         """Return the connection method."""
33         return self._connection_method
34
35     @property
36     def role(self):
37         """Return the role of the connection."""
38         return self._role
39
40     @property
41     def handshake_complete(self):
42         """Return the handshake status."""
43         return self._handshake_complete
44
45     @property
46     def is_connected(self):
47         """Check if the device is connected."""
48         raise NotImplementedError()
49
50     @property
51     def SENTINEL(self):
52         """Return the sentinel command."""
53         return self._SENTINEL
54
55     # METHODS
56     def connect(self):
57         """Connect to the device."""
58         raise NotImplementedError()
59
60     def disconnect(self):

```

```

61     """Disconnect from the device."""
62     raise NotImplementedError()
63
64     def send_sentinel(self):
65         """Send a sentinel to the IO controller (RPI)."""
66         raise NotImplementedError()
67
68     def send(self, command):
69         """Send a command to the device."""
70         raise NotImplementedError()
71
72     def message_waiting(self):
73         """Check if a message is waiting."""
74         raise NotImplementedError()
75
76     def receive(self):
77         """Receive data from the device."""
78         raise NotImplementedError()
79
80     def handshake(self):
81         # Depending on the role of the connector decide
82         # what to send and what to receive
83         if self._role == "FRONDEND":
84             self._frondend_handshake()
85             self._handshake_complete = True
86
87             # Empty the buffer
88             while self.message_waiting():
89                 _ = self.receive()
90
91         elif self._role == "BACKEND":
92             self._backend_handshake()
93             self._handshake_complete = True
94
95             # Empty the buffer
96             while self.message_waiting():
97                 _ = self.receive()
98
99         else:
100             raise HandshakeError("Unknown role {}".format(self._role))
101
102     def _frondend_handshake(self):
103         if not self.is_connected:
104             return False
105         # Wait for the response
106         while True:
107             # Send the hello message
108             self.send("Hello there.")
109
110             if self.message_waiting():
111                 res = self.receive()
112             else:
113                 continue
114
115             if res[0] == "Hello there general Kenobi.":
116                 return True
117             else:
118                 raise ValueError("Unexpected message: {}".format(res[0]))
119
120             raise ValueError("frondend Handshake failed")
121
122     def _backend_handshake(self):

```

```
123     # Wait for the hello message
124     while True:
125         time.sleep(0.1)
126
127         if self.message_waiting():
128             res = self.receive()
129         else:
130             continue
131
132         if res[0] == "Hello there.":
133             self.send("Hello there general Kenobi.")
134             break
135         else:
136             raise ValueError("Unexpected message: {}".format(res[0]))
```

Todo list

■ Add the foreword	ii
■ Create the abstract	iii
■ pagina nummering pas hier beginnen, voorgaande in romeinse nummering	v
■ Rephrase the text so it isn't flagged as plagiaat	1
■ citaat invoegen	3
■ aFBEELDING VAN GRAFEEN EN HEXAGONAAL BOORNITRIDE INVOEGEN	3
■ Stuk invoegen over verandering in fase plot (bode) bij verschillende massa, hoe hoger de massa hoe verder de fase drop naar beneden schuift, alles boven de grens heeft geen invloed op de opstelling	3
■ Grafiek maken van harmonische response over tijd van de gemaakte overdrachtsfunctie (zou alleen bij lage f met hoge A in trilling moeten komen)	3
■ Aantonen dat een hoge dichtheid (en dus massa) de resonantie frequentie verhogen	4
■ uitzoeken aan welke vc norm wij willen voldoen	5
■ betekenis van NIST-A norm uitzoeken	5
■ Verwijzen naar verwachte trillingen grafiek	5
■ CAD schema van de mask holder invoegen	7
■ keuze voor peek en mica onderbouwen	8
■ CAD schema van de sample holder invoegen	8
■ CAD van bracket invoegen	8
■ ref naar optosigma stage invoegen	8
■ citation invoegen	8
■ positie uncertainty invoegen	9
■ step variatie invoegen	9
■ laatste pijlen in de correcte richting zetten	9
■ citation invoegen	9
■ citation invoegen	9
■ referentie naar docs toevoegen	11
■ stukje over FTDI issue toevoegen	11
■ stukje over voordeel van runnen op IO controller toevoegen	11